

***IN THE UNITED STATES PATENT AND TRADEMARK OFFICE***

Applicant: Tadahiro OHMI et al.  
Title: VACUUM PROCESSING APPARATUS AND  
VAPOR DEPOSITION APPARATUS  
Appl. No.: 10/568,706  
International Filing Date: 8/19/2004  
371(c) Date: 4/28/06  
Examiner: Keath T. Chen  
Art Unit: 1792  
Confirmation Number: 4847

**AMENDMENT AND REPLY UNDER 37 CFR 1.111**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This communication is responsive to the Non-Final Office Action dated March 4, 2009, concerning the above-referenced patent application.

Applicants have included payment for a three-month extension of time to make this response timely.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this document.

**Remarks/Arguments** begin on page 5 of this document.

Please amend the application as follows: